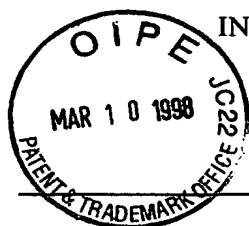


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EXAMINER INITIAL		DOCUMENT NUMBER							DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
Gm	BA	5	0	6	6	3	5	7	11/19/91	Smyth Jr. et al.	219	121.69	
Gm	BB	4	9	3	0	9	0	1	06/05/90	Johnson et al.	372	26	
Gm	BC	4	6	8	4	4	3	7	08/04/87	Donelon et al.	216	66	
Gm	BD	4	4	1	4	0	5	9	11/08/83	Blum et al.	219	121.85	

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		DOCUMENT NUMBER							DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
													YES	NO
Gm	BE		8	-	2	1	9	6	07/22/97	Japan			English	
Gm	BF		2	2	3	3	2	6	06/05/85	East Germany				German
	BG													

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

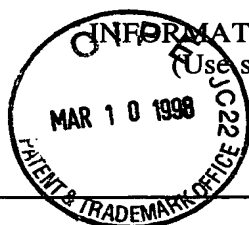
Gm	BH	Brannon, J.H., "Excimer-Laser Ablation and Etching," CIRCUITS & DEVICES magazine, September 1990 pp 19-24											
Gm	BI	Cole, H.S., Liu, Y.S., and Philipp, H.R., "Dependence of photoetching rates of polymers at 193 nm on optical absorption depth," APPL. PHYS. LETT., Vol. 48, No. 1, 6 January 1986, pp 76-77											
Gm	BJ	Dyer, P.E., and Sidhu, J., "Spectroscopic and fast photographic studies of excimer laser polymer ablation," J. APPL. PHYS. 64 (9), 1 November 1988, pp 4657-4663											
Gm	BK	4420 Laser Micromachining System - ESI Brochure (2 pages), September 1993											
Gm	BL	ESI, "Model 4570 Series Lasers Service Guide," February 1994 (REV. E 3/31/98)											
Gm	BM	Ewing, J.J., "Advanced solid-state lasers challenge conventional types," LASER FOCUS WORLD, November 1993, pp 105-110											

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							YES	NO
	AC							
	AD							

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gm	BN	Hobbs, Jerry R., "Electronics makers switch to precise micromachining tools," LASER FOCUS WORLD,						
		March 1994, pp 69-72						
gm	BO	Kulina et al., "Material bearbeitung durch Laserstrahl" no date available,						
gm	BP	Lee, Rex A. and Moreno, W.A., "Excimer vs. ND:YAG Laser Creation of Silicon Vias for 3D						
		Interconnects, IEEE, 1992, PP 358-360						
gm	BQ	Liu, Y.S., Cole, H.S., and Guida, R., "Laser ablation of polymers for high-density interconnect,"						
		MICROELECTRONIC ENGINEERING 20 (1993) 15-29, 1993 Elsevier Science Publishers B.V., pp 15-29						
gm	BR	Mahan, G.D., et al. "Theory of polymer ablation," APPL. PHYS. LETT. 53 (24), 12 December 1988,						
		pp 2377-2379						
gm	BS	Owen, Mark, "New Technology for Drilling Through - and Blind-Vias in Copper Clad Reinforced Circuit						
		Boards, IPC Proceedings, May 1995						
gm	BT	Saunders & Dolleymore, December 2, 1997 third party comments (pp 1-6 and sections 1 and 2),						
		and EPO Form 2022						
gm	BU	Saunders & Dolleymore, November 13, 1997 third party comments (pp 1-3), and EPO Form 2022						

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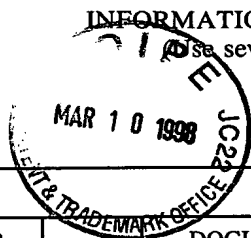
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	AD					
	AE					

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						YES	NO
	AF						
	AG						
	AH						
	AI						
	AJ						

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

Gm	BV	Srinivasan, R., and Braren, B., "Ultraviolet Laser Ablation of Organic Polymers," CHEMICAL REVIEWS, 1989, Vol. 89, No. 6
Gm	BW	Tessier, Theodore G. and Chandler, Jerry, "Compatibility of Common MCM-D Dielectric with Scanning Laser Ablation Via Generation Processes," IEEE (1993), pp 39-45
Gm	BX	"Trepanning Moves in on Mini Holes," MACHINERY AND PRODUCTION ENGINEERING, 2 November 1983, pp 42-43
Gm	BY	Wiener-Avnear, Eli, "Lasers cut microscopic paths with major potential," LASER FOCUS WORLD, July 1993, pp 75-80
Gm	BZ	Wu et al., "Single-Shot Excimer Laser Ablation of Thick Polymers Desists on Metallic Substrates," AMP Journal of Technology, Vol. 1, November 1991, pages 69-79.

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